

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: S. KADLEC, et al.

Serial No: 10/798,331

Filed: March 12, 2004

Title: METHOD FOR MANUFACTURING SPUTTER-COATED
SUBSTRATES, MAGNETRON SOURCE AND SPUTTERING
CHAMBER WITH SUCH SOURCE

Group: 1795

Examiner: Michael A. Band

Conf. No.: 6134

AMENDMENT UNDER 37 CFR 1.312

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

March 29, 2010

Sir:

The following amendments and remarks are submitted in the above-identified after Notice of Allowance and concurrently with payment of the issue fee in the application.

Amendments to the Claims

Remarks are included following the amendments.